



Radiation tolerance of Depleted CMOS (D-CMOS) sensors

G. Casse

Abstract:

The non-ionising energy lost by energetic radiation to the structure of semiconductor sensors damages the crystal and consequently modifies the electrical characteristics of the devices.

All the parameters that are relevant to the performance of the sensors are changed: the current, the full depletion voltage, the response to ionising particles (signal), the inter-electrode resistance and capacitance (in segmented detectors). These changes are degrading the performance of the sensors and lead to their failure after significant fluences of impinging particles. The design of the sensors can be engineered to increase the failure fluence. Most of the radiation hardening was performed with hybrid segmented silicon sensors. Can this results be applied to deep depleted CMOS detectors?

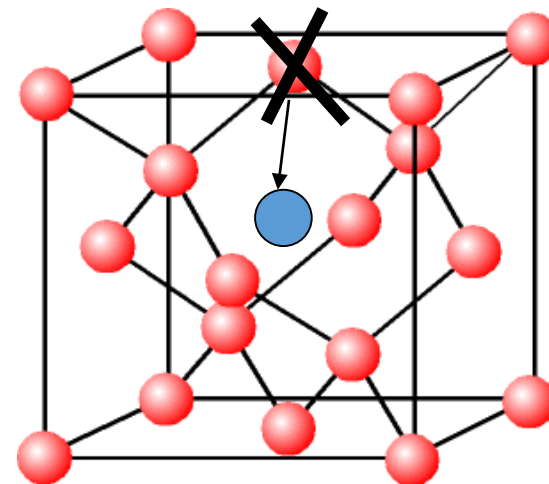
OUTLINE:

- What defines radiation tolerance
 - Radiation damage in silicon
 - Effects on detector performances
- Mitigation of sensor's degradation
- D-CMOS: can they be designed radiation-hard?

Radiation with protons/neutrons

Surface damage: ion trapping in SiO_2 , leading to charge on Si-SiO₂ interface. Sensor design must be robust against this (not discussed here).

Bulk damage: displacement of Si atoms within the crystal leaves vacancies and interstitials (defects).



- Energy needed to displace atom from lattice=15eV

- Damage energy dependent

 - < 2 keV ⇒ isolated point defect

 - 2-12 keV ⇒ defect cluster

 - >12 keV ⇒ many defect clusters

- This damage is called:

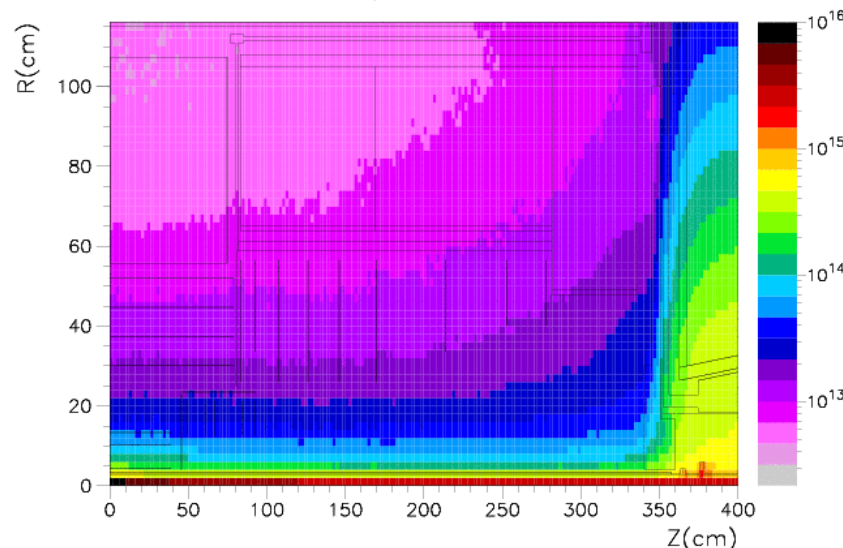
Non-Ionizing Energy Loss (NIEL)

 - Results scaled to 1MeV neutrons

 - (e.g. ATLAS ID up to $\sim 2 \times 10^{14} \text{ n}_{\text{eq}} \text{ cm}^{-2} \text{ yr}^{-1}$)

- Electrons and photons don't make defects!

1 MeV equivalent neutrons



What radiation levels?

$e^+e^- 10^{12} \text{ n}_{\text{eq}} \text{ cm}^{-2}$

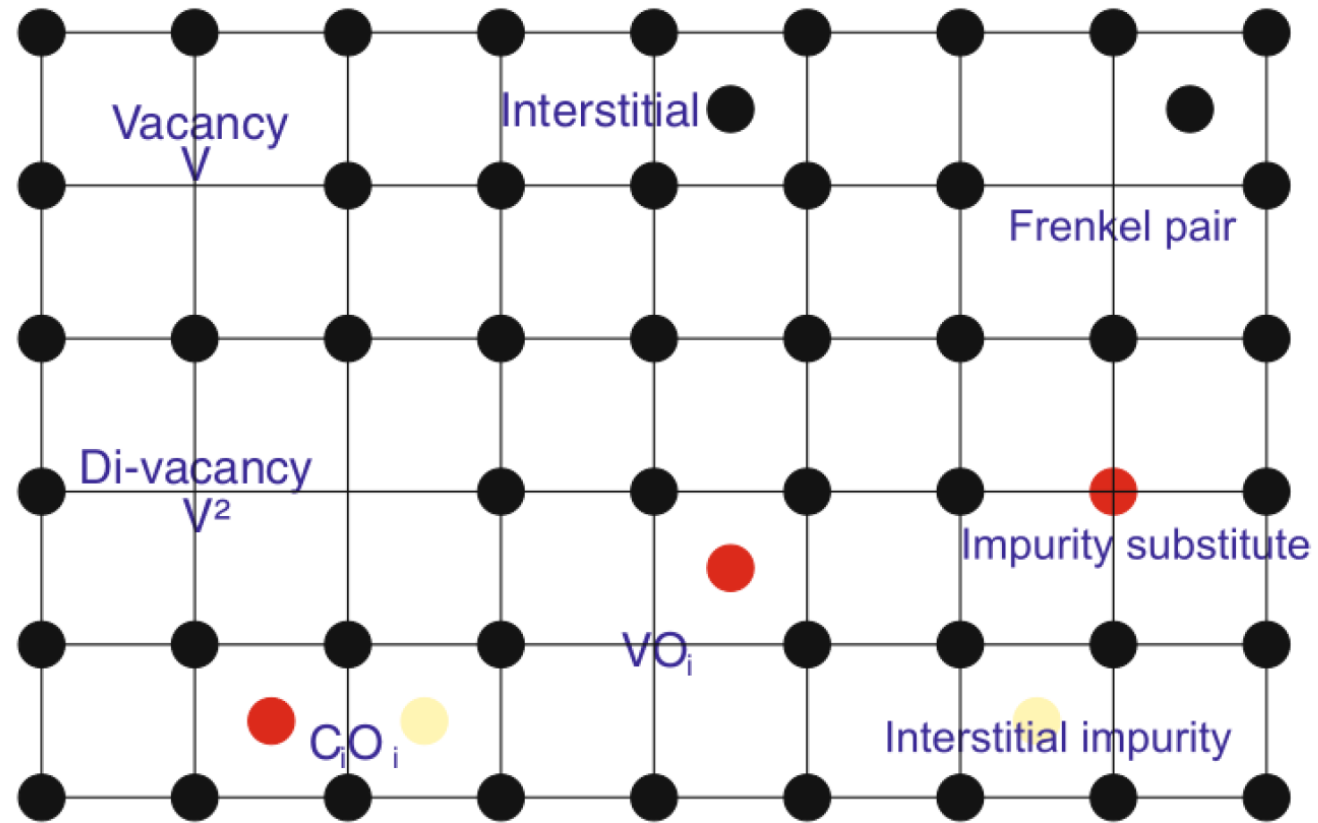
LHC $2 \times 10^{15} \text{ n}_{\text{eq}} \text{ cm}^{-2}$

HL-LHC $3 \times 10^{16} \text{ n}_{\text{eq}} \text{ cm}^{-2}$

FCC $7 \times 10^{17} \text{ n}_{\text{eq}} \text{ cm}^{-2}$

Microscopic view...

The damaged lattice 'zoo'



J. Zhang

A fully depleted (array or matrix) silicon diode is a particle detector

Many diodes: p-strips in n-bulk

Positive (reverse-bias) voltage applied via conductive back-plane.

Depletes the detector and provides E-field for charge collection.

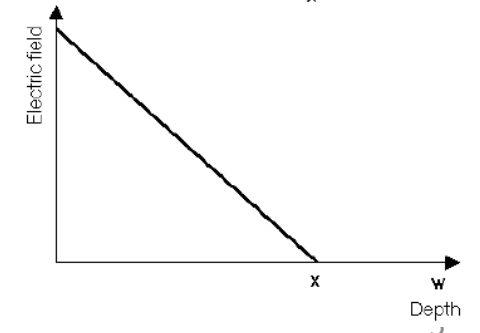
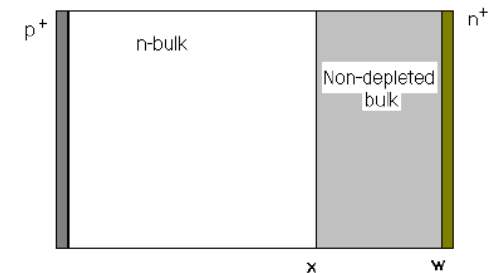
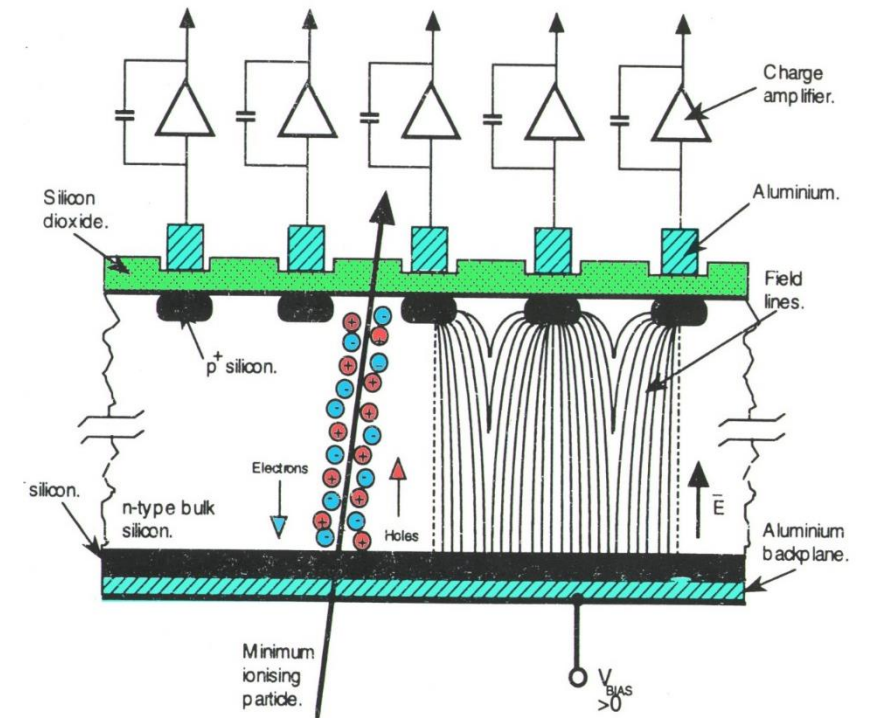
Deposited charge moves to nearest strip.

Typical signal

- 8900 e/h pairs/100 μm
- typical size of the charge cloud $\sim 10 \mu\text{m}$

Here: signal readout via Al strip, capacitively coupled to p-strip (SiO_2 in between).

(prevents large currents flowing through amplifier, but reduces collected charge.)



Effects of Radiation damage to silicon detectors

Defects in the lattice leave extra energy levels in band-gap.

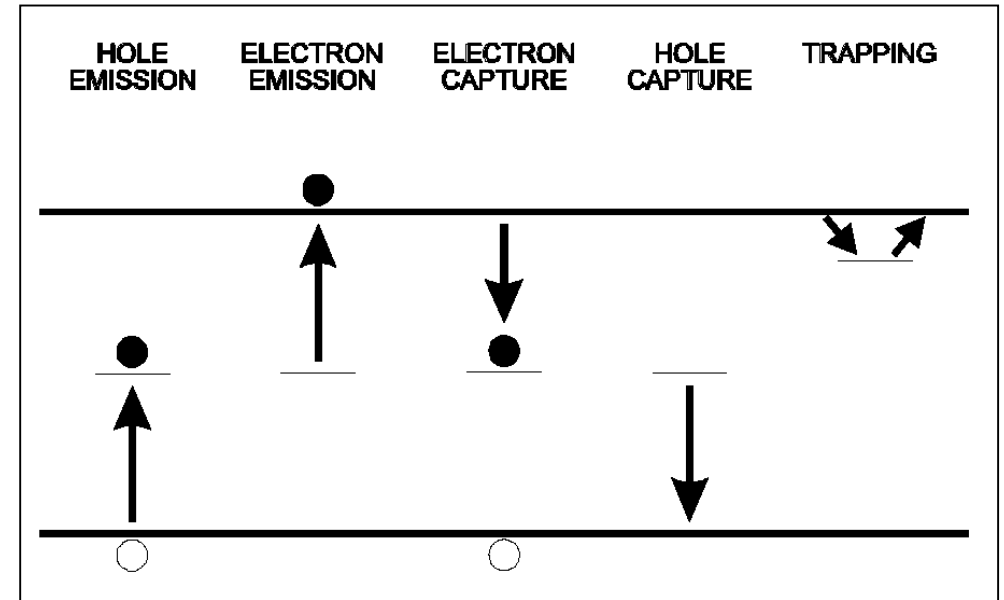
These can:

- donate electron/holes
- capture electron/holes (trapping)
- increase leakage current (two-step transitions valence to conduction band)
- act as recombination centres

Damaging effects on Silicon detectors:

- increased leakage currents
- type-inversion (change of effective doping type)
- reduced charge collection efficiency and charge carrier mobility

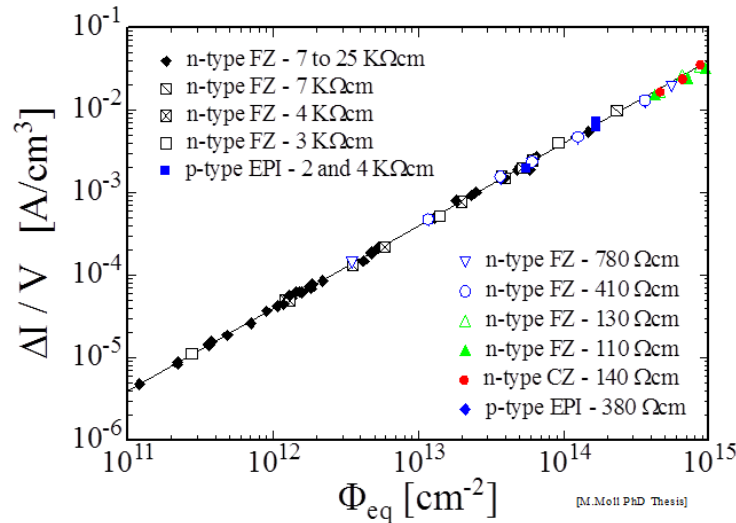
Detailed behaviour depends on many factors (e.g. other impurities present)



Change of leakage current and depletion voltage

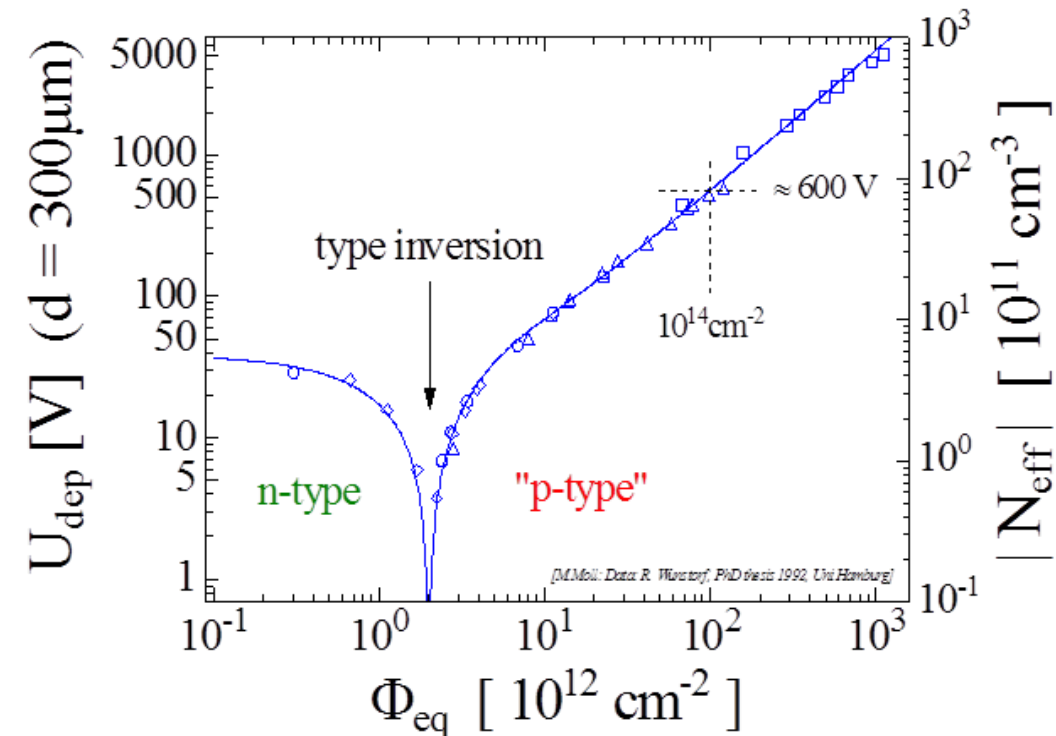
- The leakage current of a sensor, at constant temperature, increases with NIEL
- The damage parameter doesn't depend on Silicon resistivity, bulk type, fabrication technology, ...

$$\alpha = \frac{\Delta I}{V \cdot \Phi_{eq}}$$



M. Moll

Before inversion, in p-in-n sensors, the junction is on the segmented side. After inversion the junction moves to the back side.

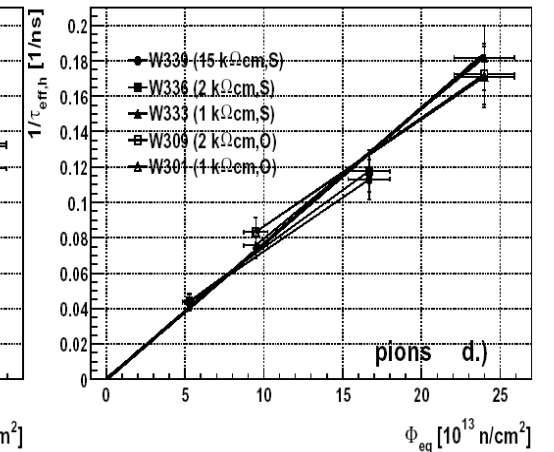
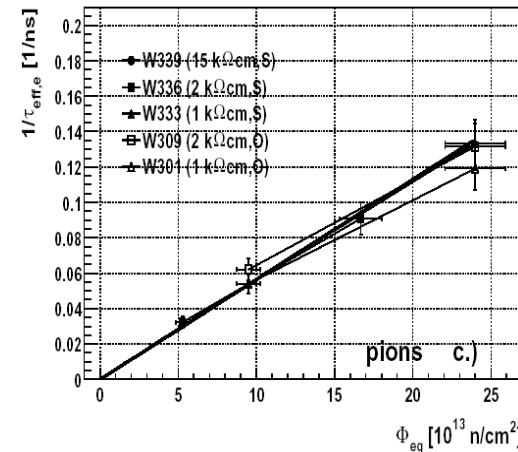


Change of charge collection efficiency

- The irradiation introduces defects which act as trapping center for the charge generated by an ionizing particle
- This reduce the overall signal thus affecting the detector efficiency

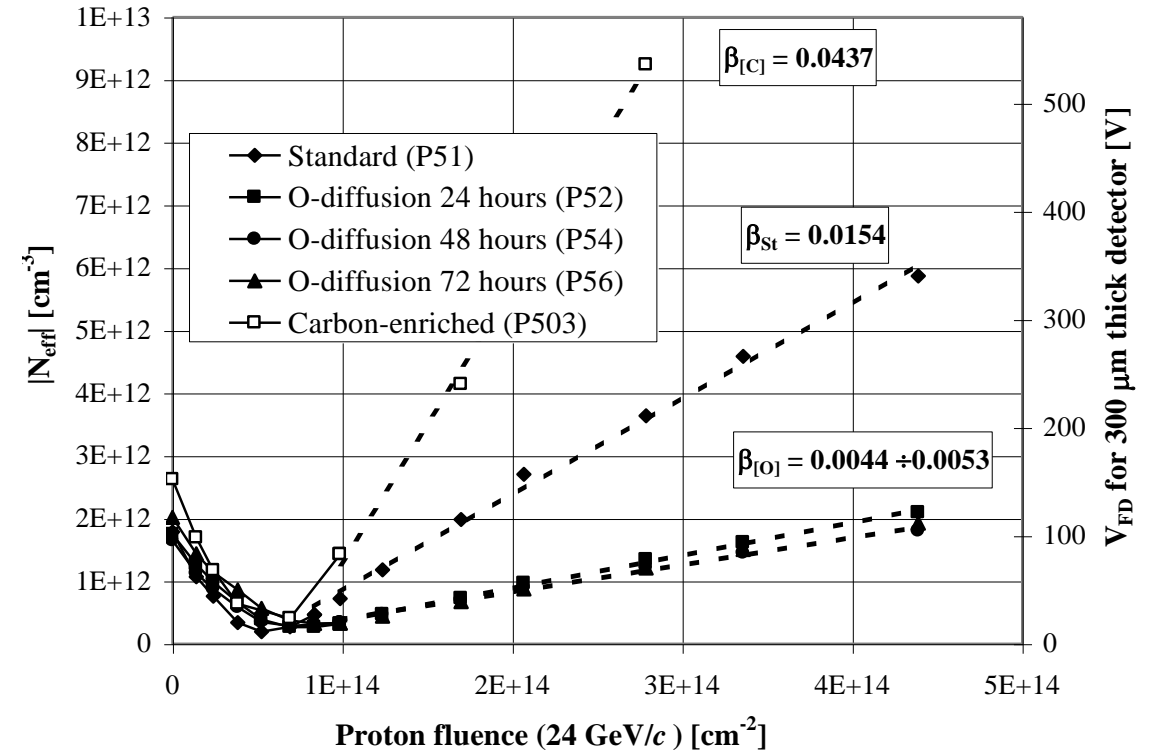
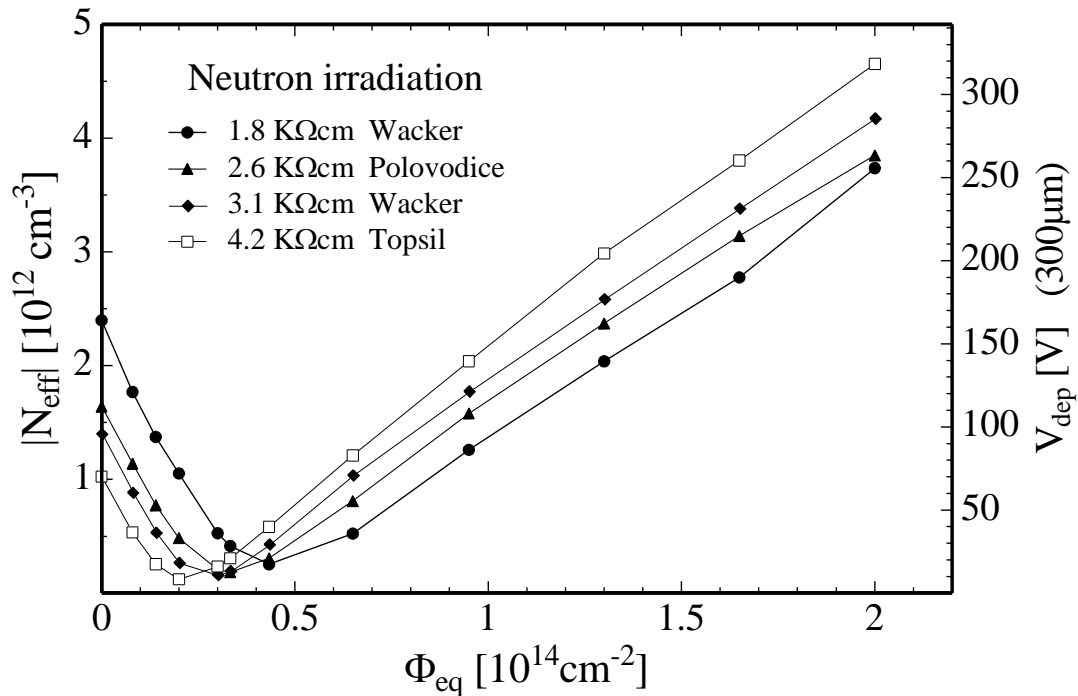
$$Q_{e,h}(t) = Q_{0e,h} \exp\left(-\frac{1}{\tau_{eff\ e,h}} \cdot t\right) \quad \frac{1}{\tau_{eff\ e,h}} = \beta_{e,h}(T, t) \Phi_{eq}$$

- When the effective trapping time becomes of the order of the electron/hole drift time (5-20ns) the charge integrated at the electrodes by the front-end electronics is reduced



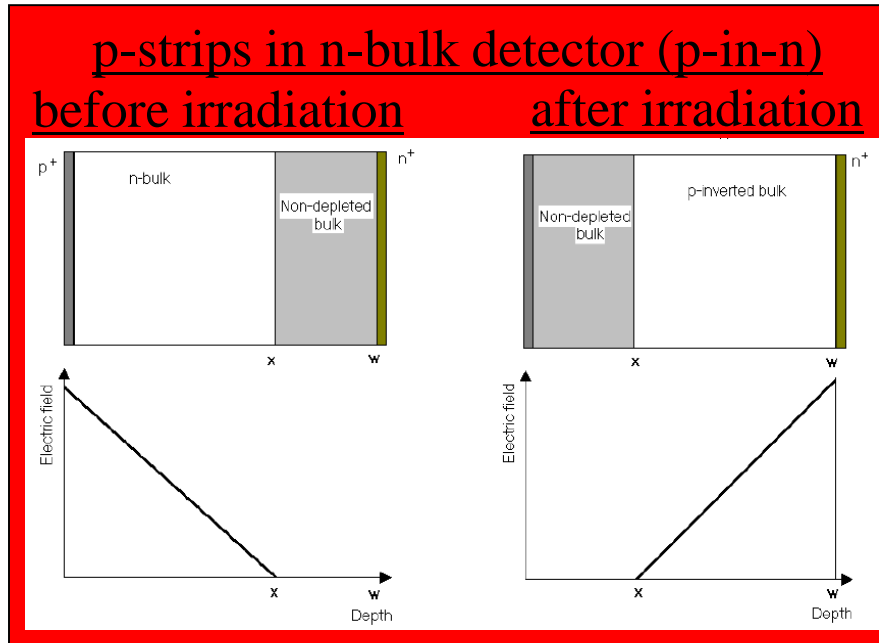
Radiation tolerance prediction: “old” method

What metric do we use for assessing the radiation tolerance of a given sensor?



“Good” operation of sensors was based on the ability to provide a bias voltage corresponding to 120-130% of the full depletion voltage. But the VFD would be well over 10000V at HL-LHC doses

Under-depleted detectors

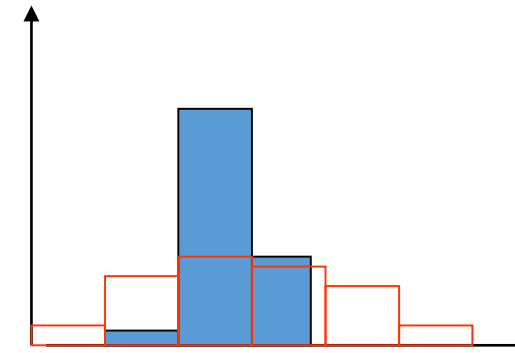


Undepleted region acts like an ohmic resistor.

- no effective conduction
- no/weak field to collect charge to the nearest strip (relying on diffusion)

If detector is partially depleted:

- near the strip side
 - ⇒ only charge in depleted region contributes
 - ⇒ smaller signal, same spatial resolution
- near the backplane
 - ⇒ carriers travel towards strips, but don't reach it
 - ⇒ signal spread over many strips
 - ⇒ poor spatial resolution

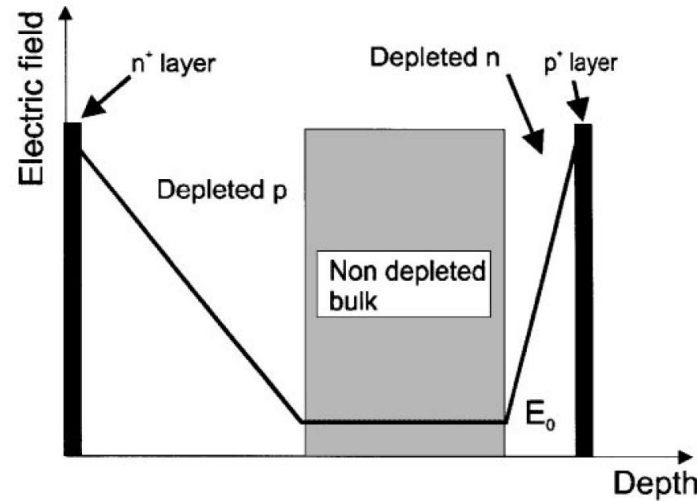


N-side read-out better for irradiated devices. Can we estimate the effect of charge trapping on the signal?

Schematic changes of Electric field after irradiation

Effect of trapping on the Charge Collection Efficiency (CCE)

Collecting electrons provide a sensitive advantage with respect to holes due to a much shorter t_c . P-type detectors are the most natural solution for e collection on the segmented side.



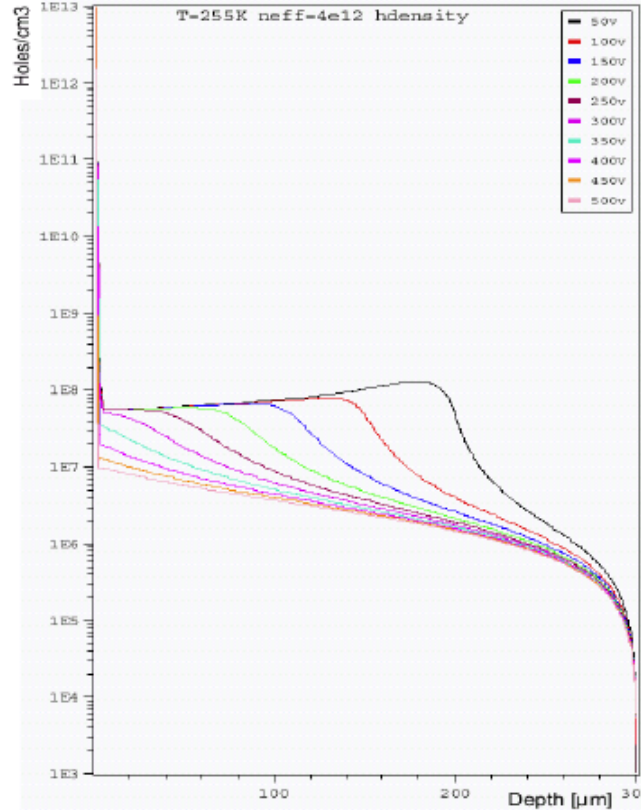
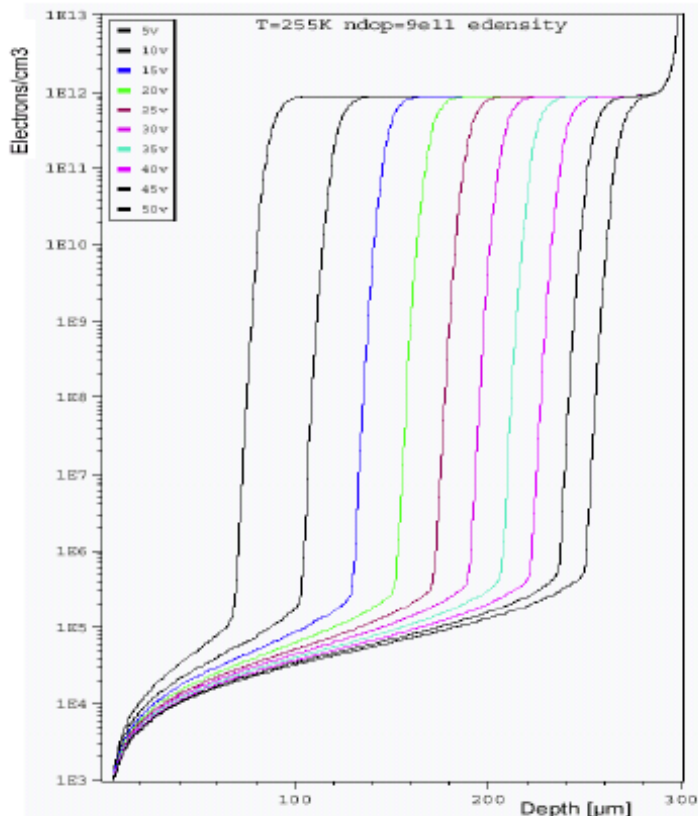
There is electric field throughout the detector, undepleted bulk is not a correct statement after significant irradiation.

$$Q_{tc} \cong Q_0 \exp(-t_c/\tau_{tr}), \quad 1/\tau_{tr} = \beta\Phi.$$

N-side read out to keep lower t_c

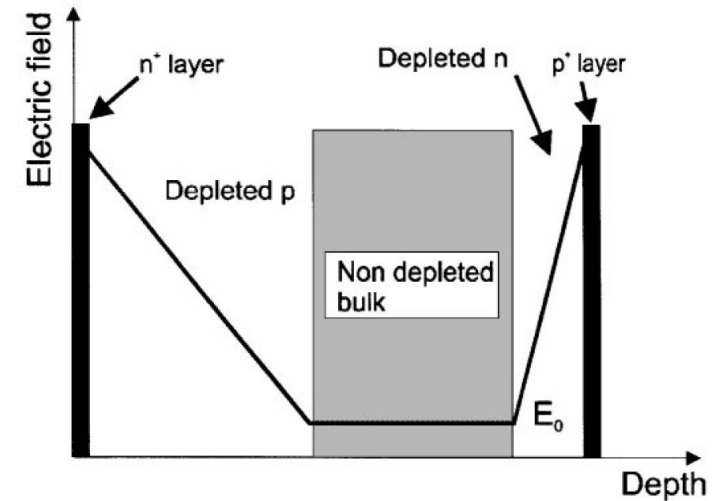
The simplified approach of VFD does not hold for high radiation levels

Majority carrier concentration at different bias voltages. Unirradiated sensors



After $2E14 n_{eq} cm^{-2}$

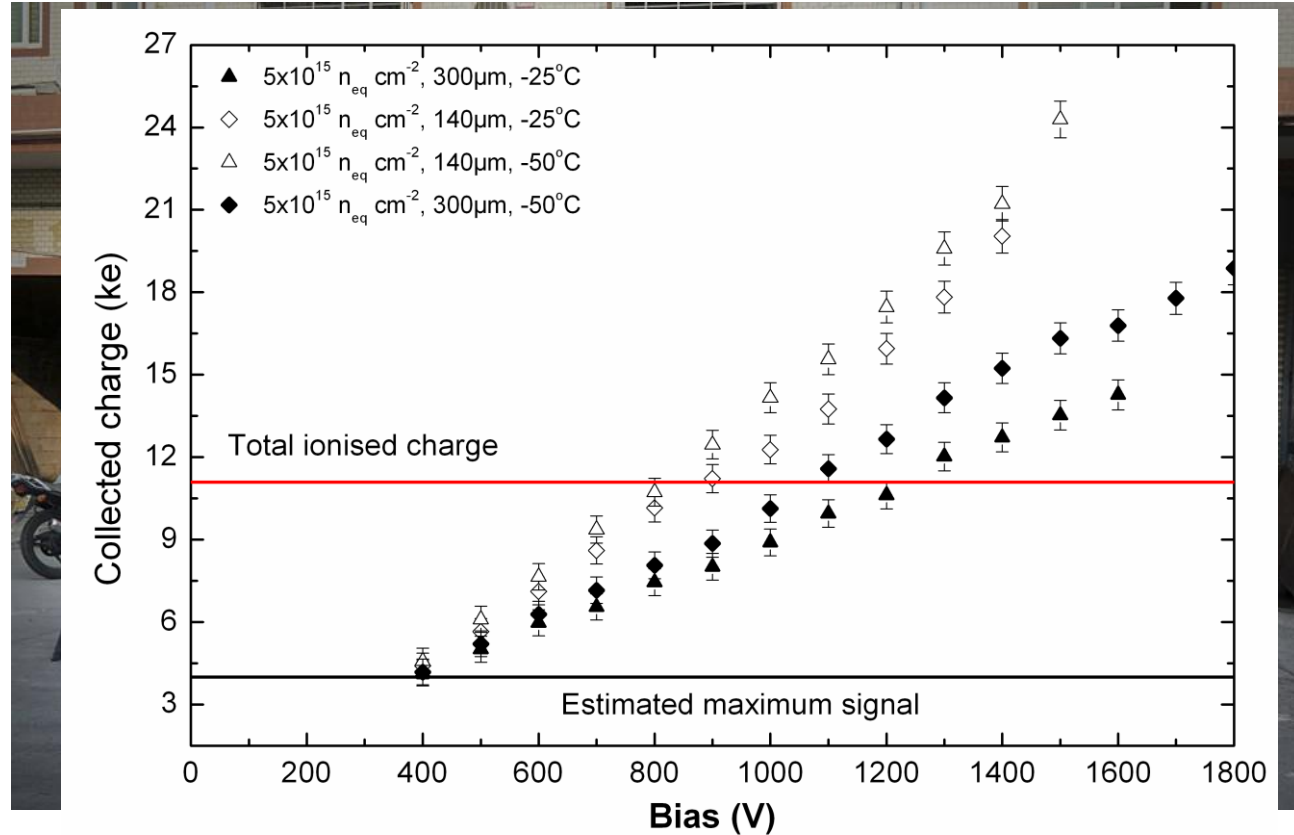
There is electric field throughout the detector, undepleted bulk is not a correct statement after significant irradiation.



RD50 Charge multiplication

Some times, things go better than planned, a good day out fishing

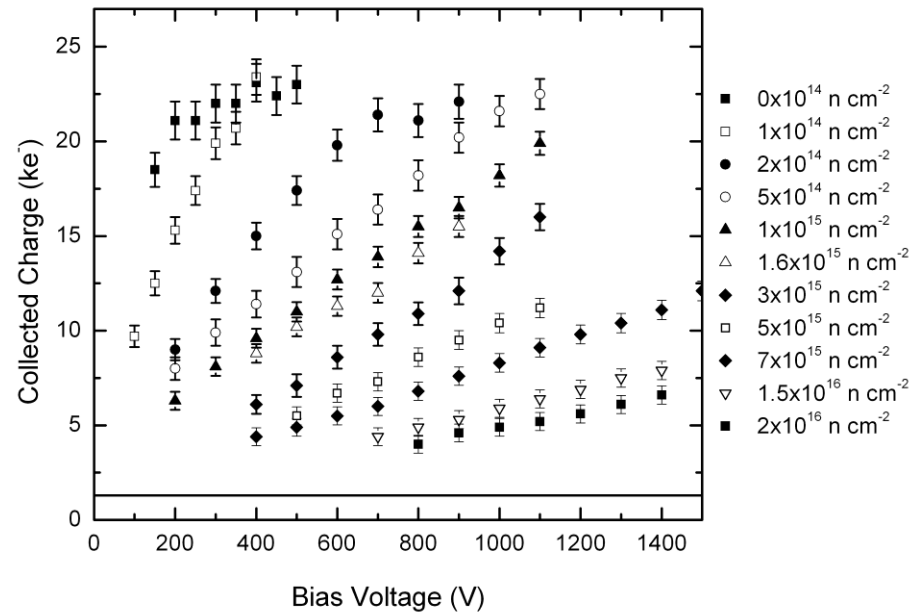
G. Casse, A. Affolder, P.P. Allport, H. Brown, I. McLeod, M. Wormald
"Evidence of enhanced signal response at high bias voltages in planar silicon detectors irradiated up to $2.2 \times 10^{16} \text{ n}_{\text{eq}} \text{ cm}^{-2}$ ", NIMA Vol. 636 (2011).



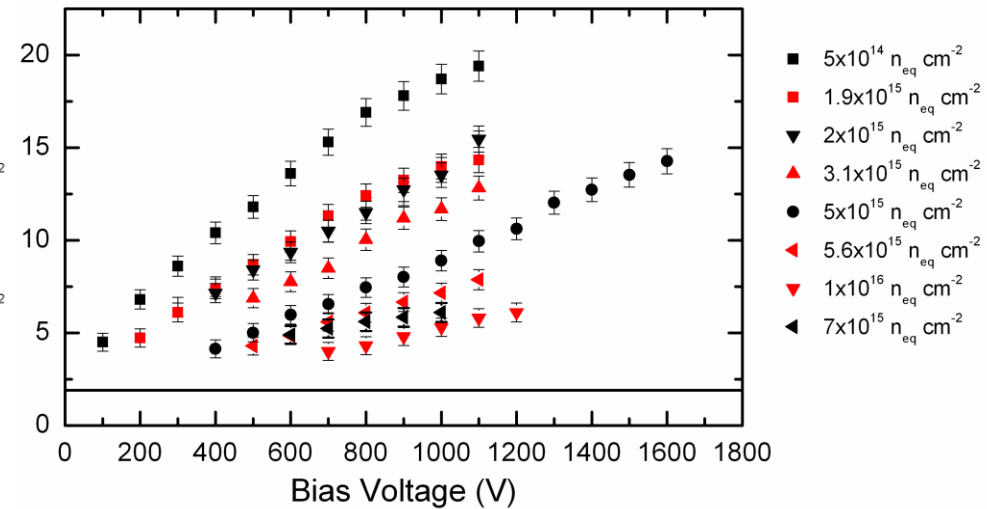
Or more charge than you expect after irradiation

Results with proton irradiated 300 μm n-in-p Micron sensors (up to $1 \times 10^{16} \text{ n}_{\text{eq}} \text{ cm}^{-2}$)

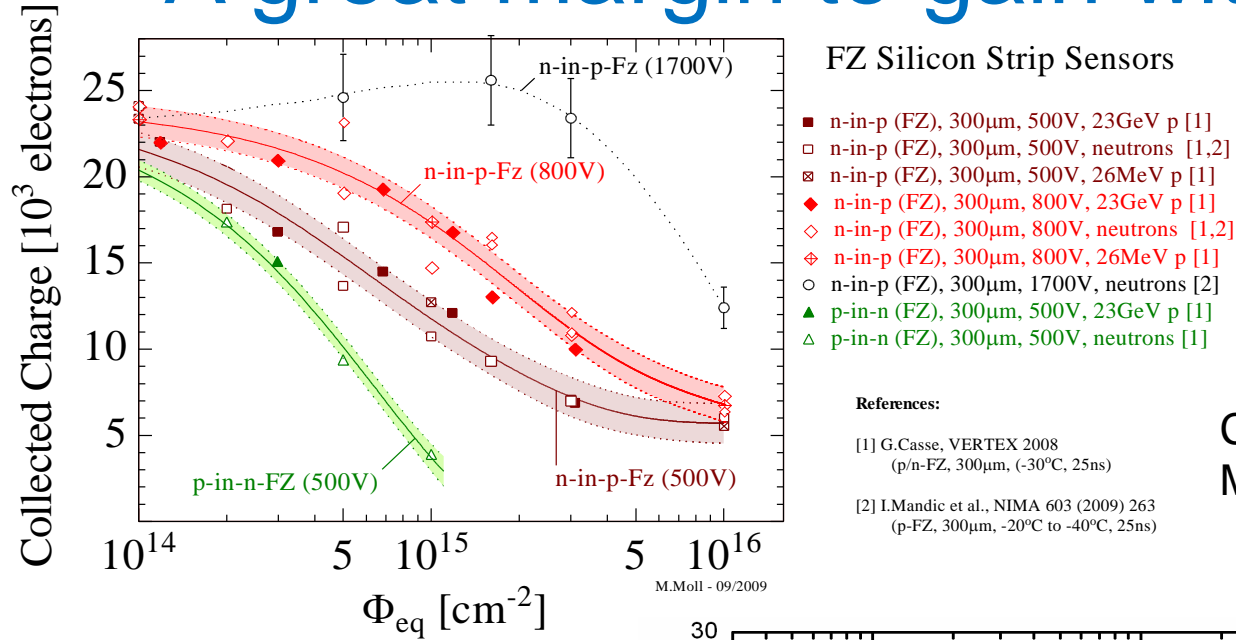
Irradiated with reactor
neutrons



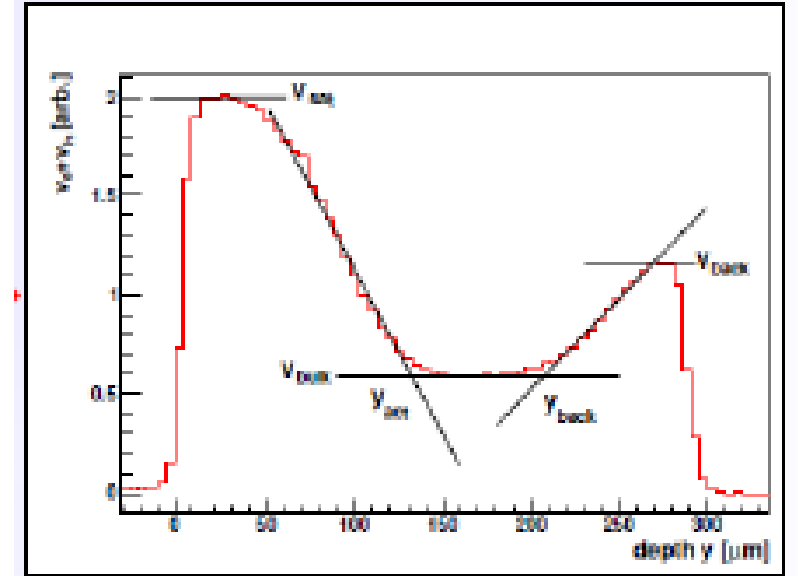
RED: irradiated with
24GeV/c protons
Other: 26MeV protons



A great margin to gain with extremely high voltage

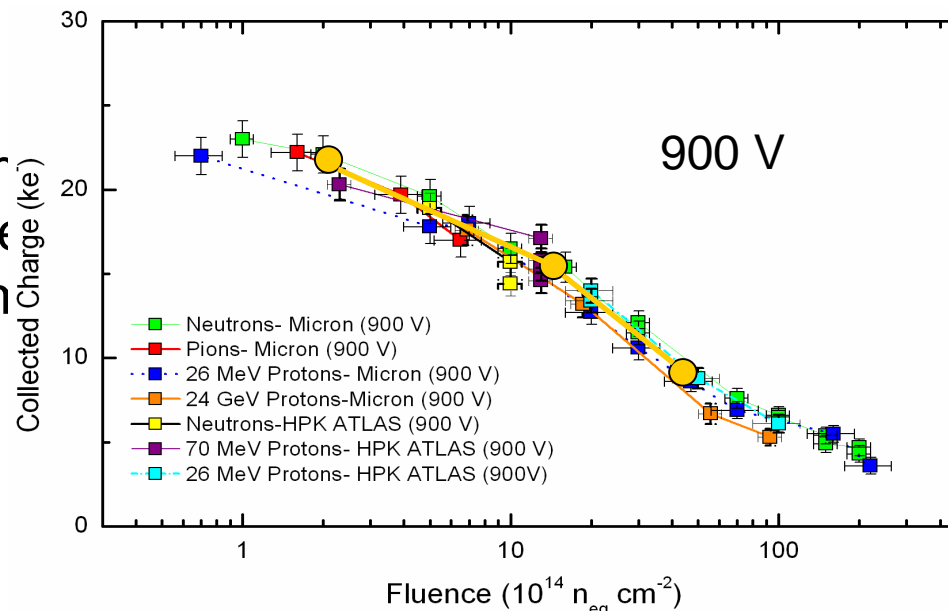


[G.Kramberger et al., PoS (Vertex 2012) 022]



Compiled by
M. Moll

..but good agreement among measurements from different groups and sensors from different manufacturers

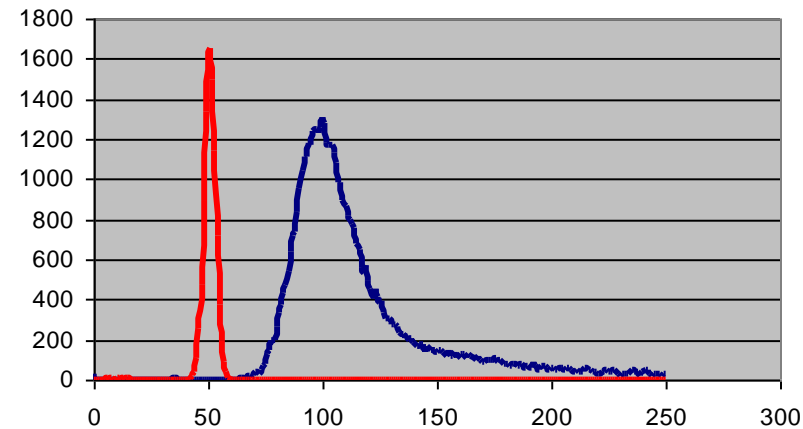


... and at the end of the day a good metric is S/N

We have learned that a signal exceeding 4000 e⁻ can be extracted from planar sensors irradiated to 2E16 n_{eq} cm⁻², if we make this enough we achieve phenomenally high radiation tolerance.

Lets say, with S/N > 5 (ENC < 800).

Typically, highly segmented hybrid sensors exhibit ENC ranging from 300 to 1500 e⁻.



Mitigation of sensor degradation

One essentially needs:

- Very high Electric field (voltage)
- Low noise

Parameters: Sensor geometry,
operation conditions (cooling)

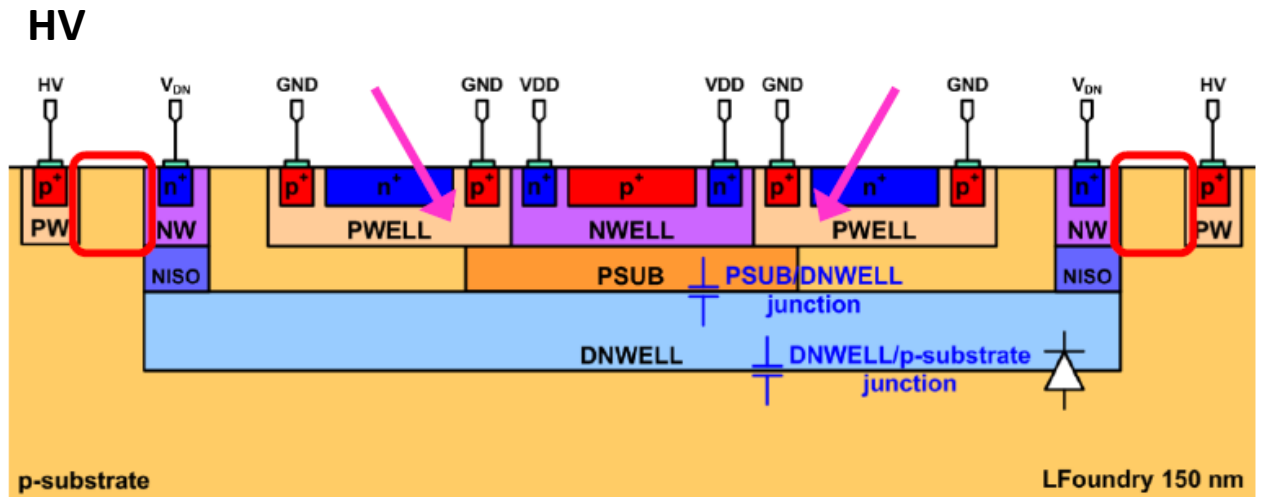
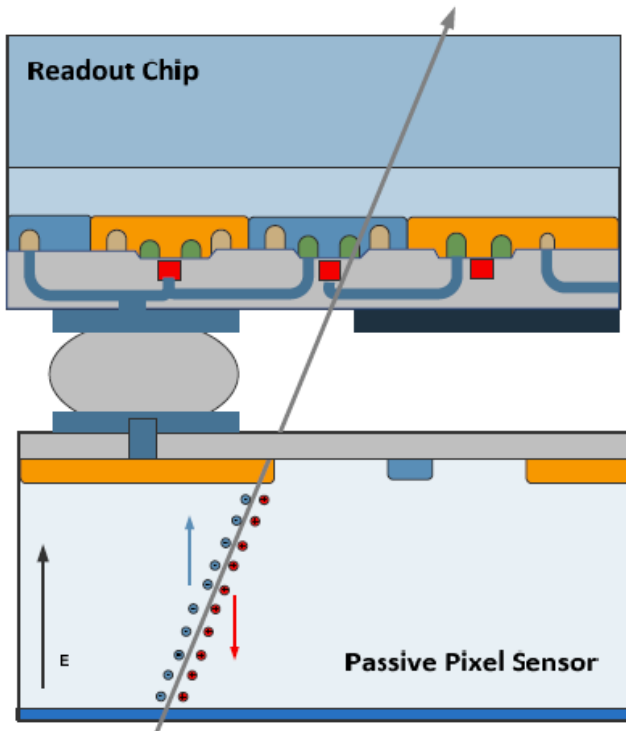
Parameters: Sensor geometry,
operation conditions (cooling),
electronics

At intermediate radiation damage one can
play other tricks:

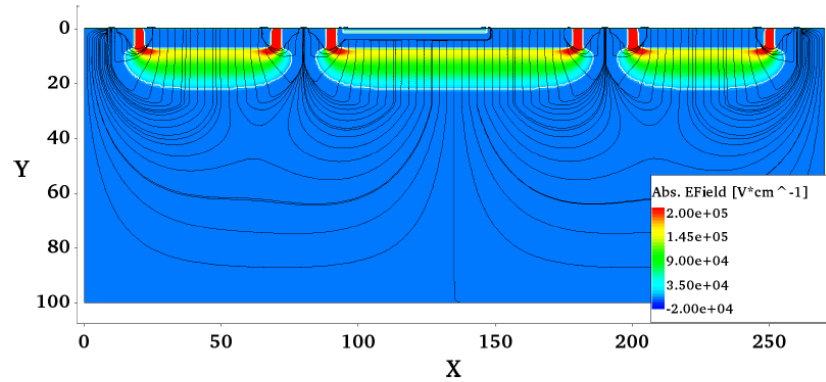
Choice of bulk resistivity

Choice of bulk type (impurity content)

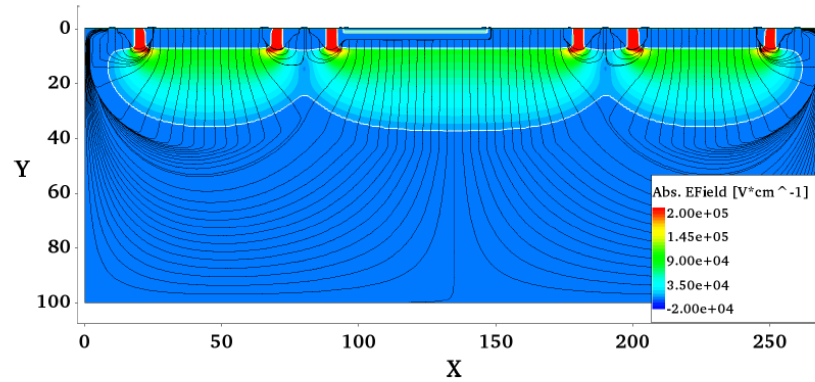
Applying High Voltage to D-CMOS



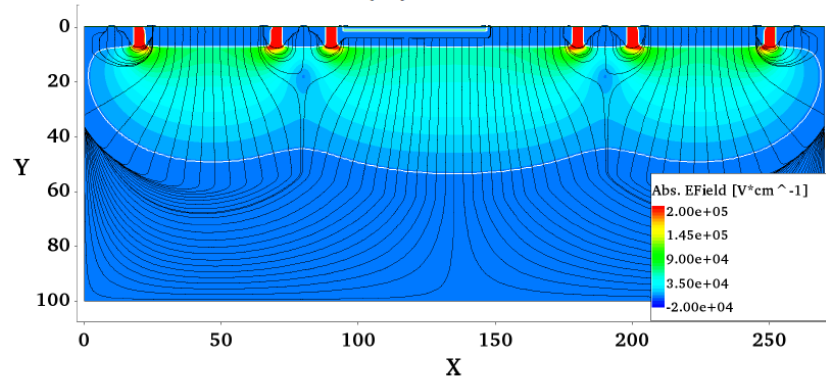
Applying High Voltage to D-CMOS: Top biasing



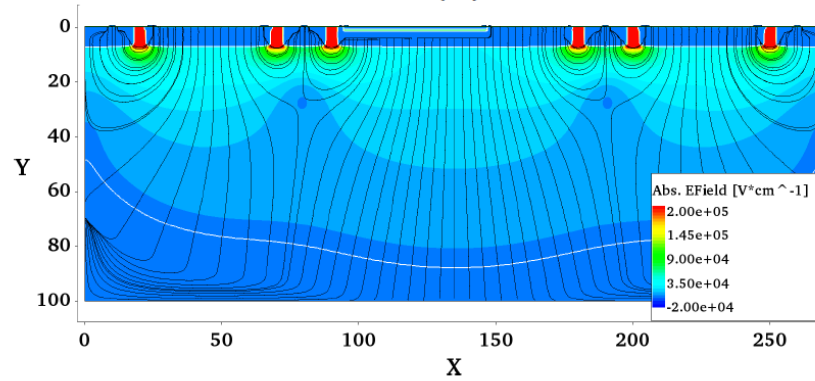
(a)



(b)



(c)

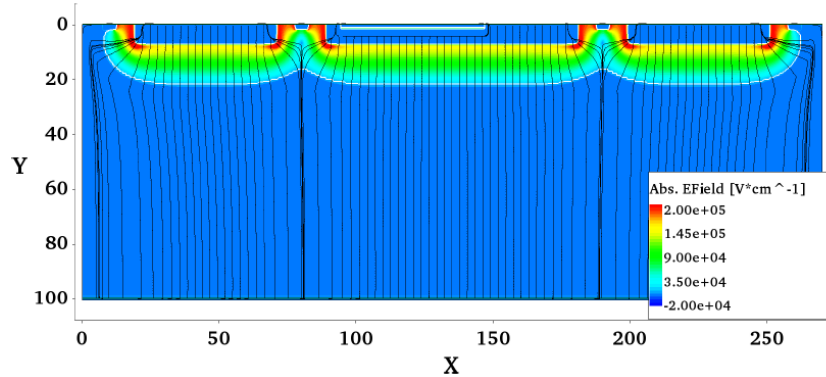


(d)

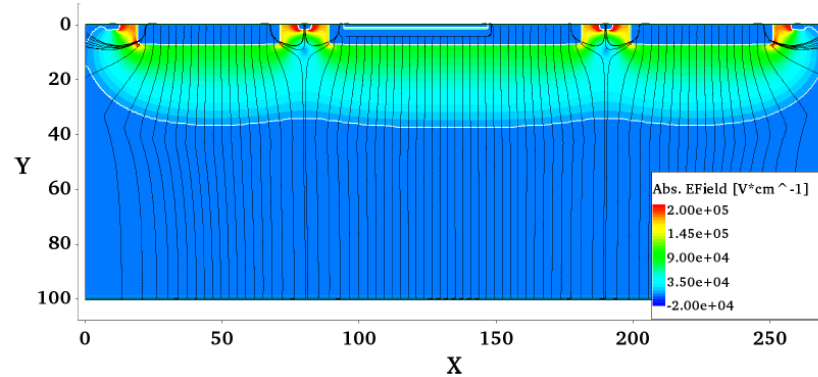
From Lingxin Meng PhD thesis.

Figure 5.8: Absolute electric field strength of H35DEMO for resistivities 20 (a), 80 (b), 200 (c) and 1000 Ωcm (d), biased from the top at -120 V for the standard layout.

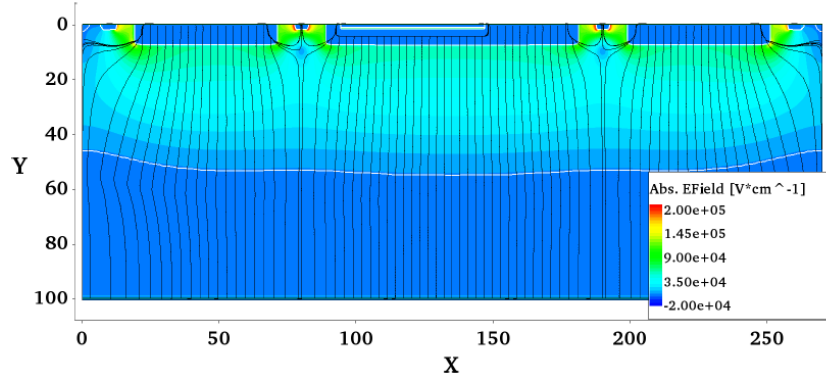
Applying High Voltage to D-CMOS: Backside biasing



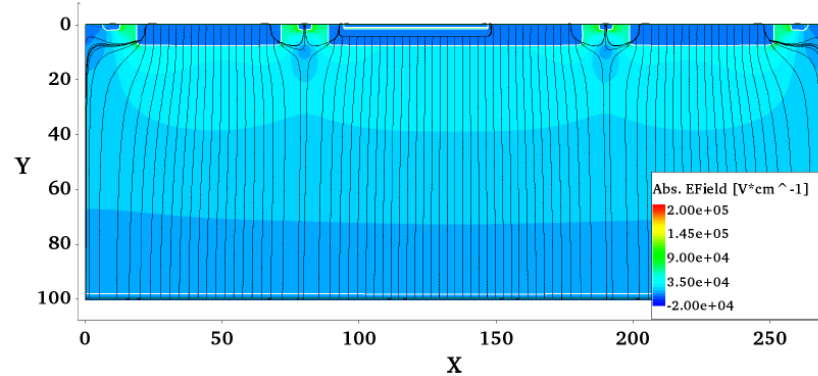
(a)



(b)



(c)



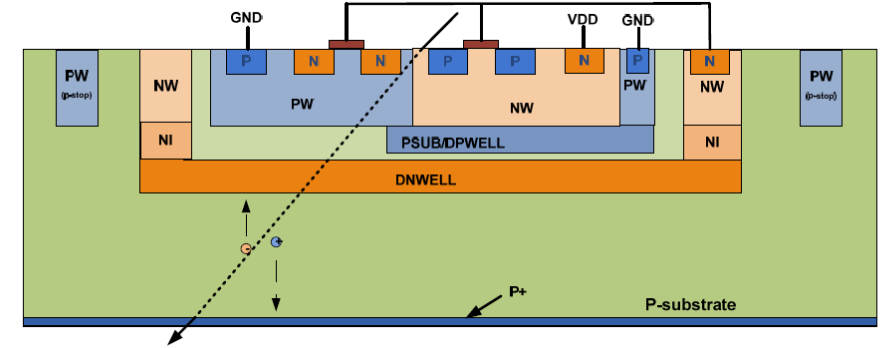
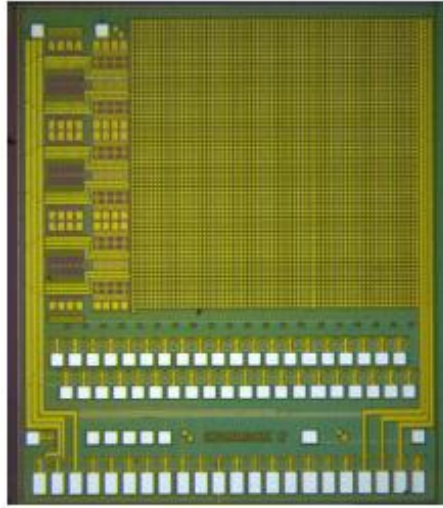
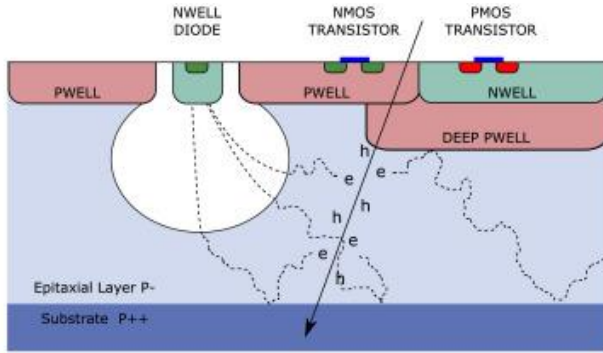
(d)

From Lingxin Meng PhD thesis.

It is possible, with careful design, to apply HV to D-CMOS devices

Figure 5.10: Absolute electric field strength of H35DEMO for resistivities 20 (a), 80 (b), 200 (c) and 1000 Ωcm (d), biased from the back at -120 V for the standard layout with back side process.

How do D-CMOS compare to hybrid detectors for noise?



ALPIDE $\sim < 10 e^-$ noise

ALPIDE, the Monolithic Active Pixel Sensor for the ALICE ITS upgrade, M. Mager et al., NIM A Volume 824, 11 July 2016, Pages 434-438

Typically, with monolithic HV-CMOS, can achieve a $< 60 e^-$ equivalent noise charge.

How do D-CMOS compare to hybrid detectors for noise?

Capacitive coupled hybrid detector

CCPD1 - capacitive coupled pixel detector

Pixel size 55x55 μm

Noise 70e

Time resolution <100ns

MIP SNR 25

CCPD2 (CAPPIX) - capacitive coupled pixel detector

Pixel size 50x50 μm

Noise 30-40e

Time resolution <300ns

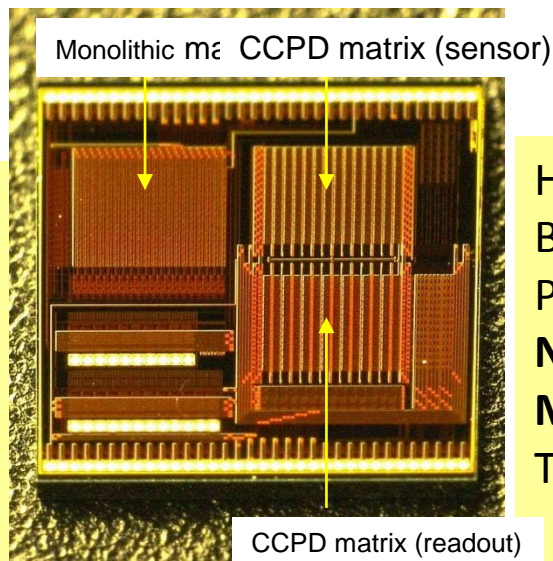
MIP SNR 45-60

Irradiations of test pixels

60MRad – MIP SNR 22 at 10C (CCPD1)

$10^{15}\text{n}_{\text{cm}^2}$ MIP SNR 50 at 10C (CCPD2)

Technology 350nm HV – substrate 20 Ωcm uniform



Monolithic detector - frame readout

HVPixel – **CMOS in-pixel electronics with hit detection**

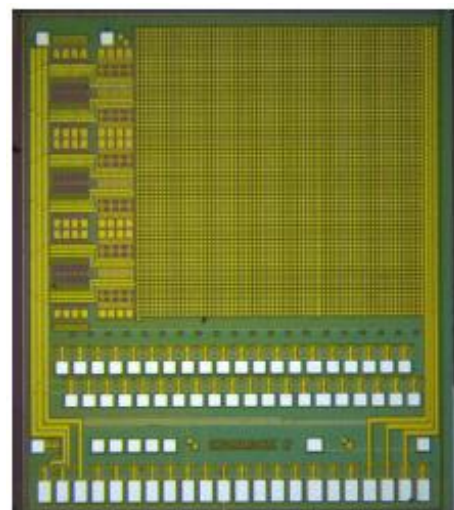
Binary RO

Pixel size 55x55 μm

Noise 60e

MIP seed pixel signal 1800 e

Time resolution <100ns



HVPixelM chip - frame mode readout

Pixel size 21x21 μm

4 PMOS pixel electronics

128 on-chip ADCs

Noise: 21e (lab) - 44e (test beam)

MIP signal - cluster: 2000e/seed: 1200e

Test beam: **Detection efficiency >98%**

Seed Pixel SNR ~ 27

Cluster signal/seed pixel noise ~ 47

Spatial resolution ~ 3 μm

A few results with D-CMOS

Other relevant metrics!

Non irradiated sensor for mu3e.

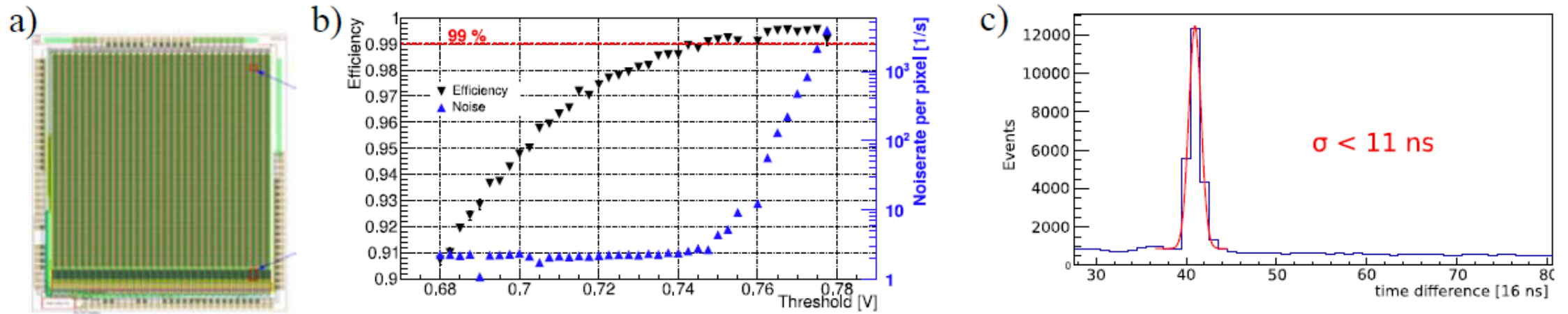


Figure 10 Layout of a) the MuPix7 chip and its measured performance b) hit detection efficiency and c) time stamping resolution (from [12]).

Radiation hardening of D-CMOS

M. Benoit et al., Characterization Results of a HVCMOS Sensor for ATLAS, NIMA

Max irradiation $5 \times 10^{15} \text{ n}_{\text{eq}} \text{ cm}^{-2}$.

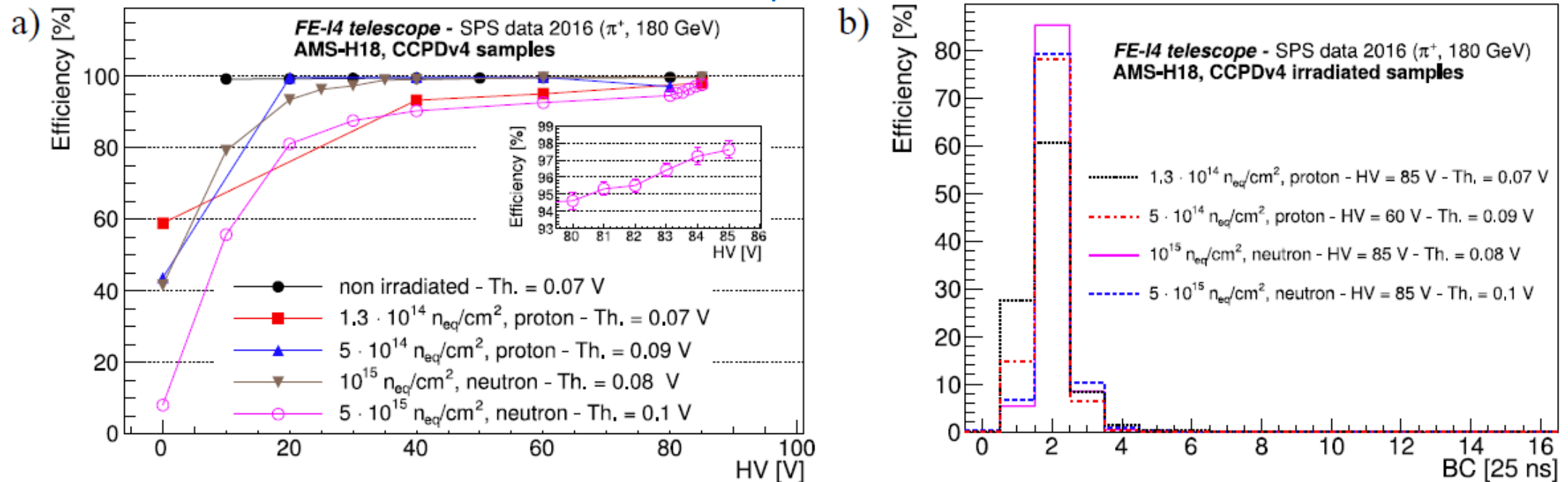
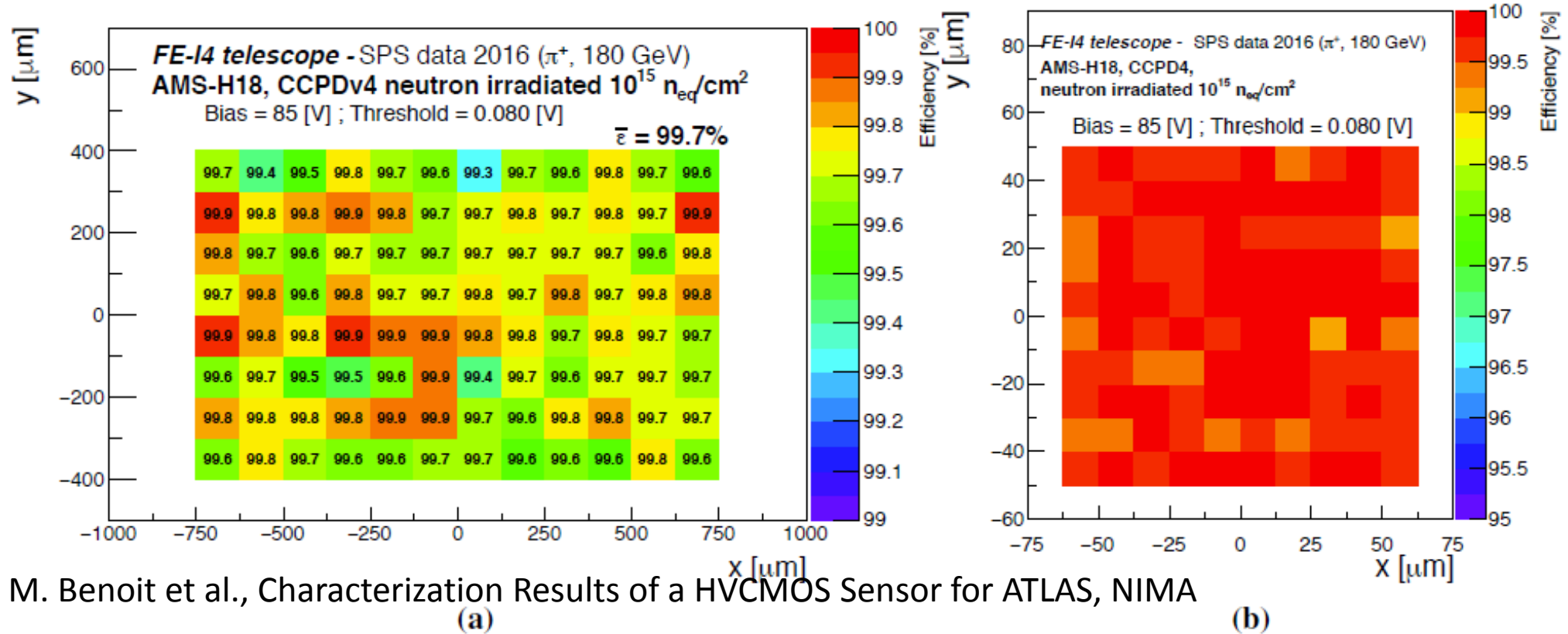


Figure 11 The measurement results of CCPDv4 devices a) track detection efficiency for different neutron dose, threshold and bias b) time stamping resolution (from [14])

M. Benoit et al., Test beam measurement of ams H35 HV-CMOS capacitively coupled, JINST 13 (2018) no.12, P12009

Radiation hardening of D-CMOS



M. Benoit et al., Characterization Results of a HVCMOS Sensor for ATLAS, NIMA

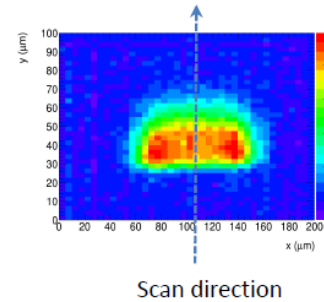
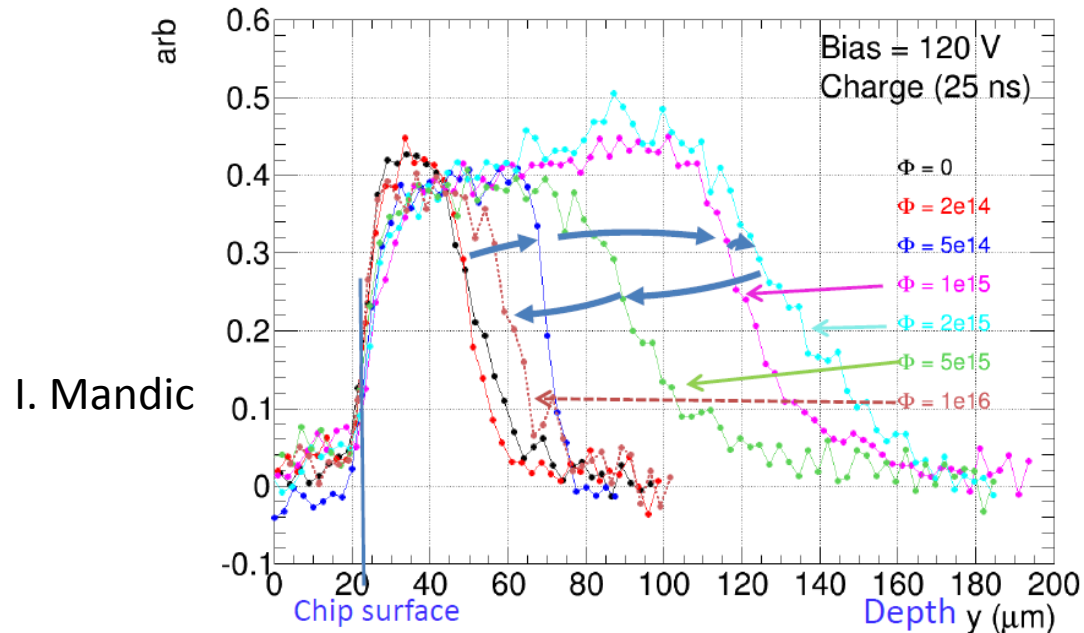
Figure 5. a) Hit efficiency map for CCPDv4 neutron-irradiated with $1 \times 10^{15} n_{eq}/cm^2$; the colour scale is only ranging from 99% to 100%. b) Sub-pixel hit efficiency map overlaid from all central pixels. No significant efficiency loss is visible in any region of the pixel. The threshold of 80 mV is assumed to be equivalent to $690 e^-$ according to [11].

M. Benoit et al., Test beam measurement of ams H35 HV-CMOS capacitively coupled, JINST 13 (2018) no.12, P12009

Radiation hardening of D-CMOS

Charge collection profile, AMS (20 Ωcm)

Reactor neutrons, steps: $2e14$, $5e14$, $1e15$, $2e15$, $5e15$, $1e16$



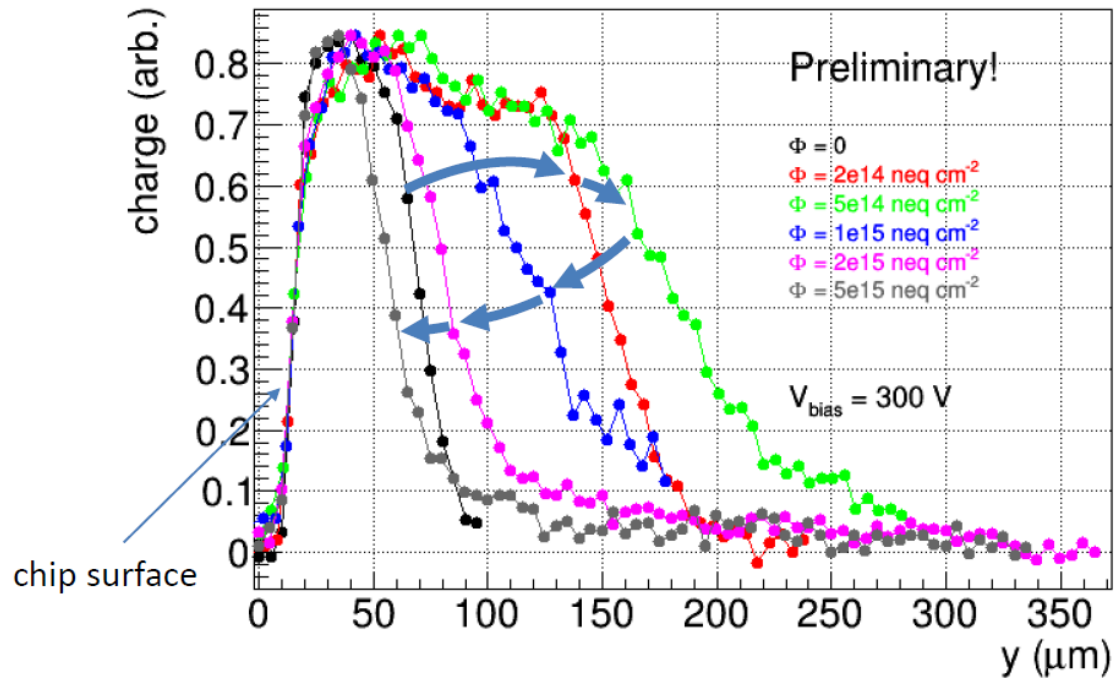
Some consequence of the relatively low resistivity of CMOS wafer substrates. It can impact on sensor performance at low/intermediate irradiation levels.

- charge collection width increases with fluence up to $\sim 2e15$ n/cm²
 - initial acceptor removal
- charge collection width falls with fluences above $\sim 2e15$ n/cm²
 - initial acceptor removal finished, space charge concentration increases with irradiation
- **at $1e16$ charge collection width still larger than before irradiation**

Radiation hardening of D-CMOS

Charge collection profile, Xfab (100 Ωcm)

Reactor neutrons, fluence steps: $2e14$, $5e14$, $1e15$, $2e15$, $5e15$



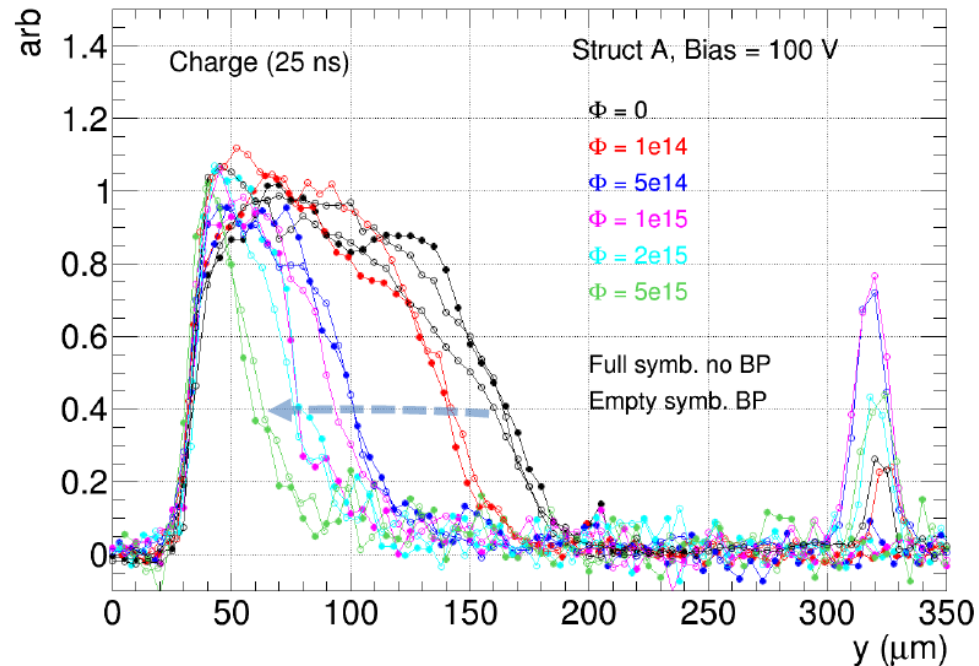
Some consequence of the relatively low resistivity of CMOS wafer substrates. It can impact on sensor performance at low/intermediate irradiation levels.

- large increase of charge collection region at lower fluence than AMS
- at $5e15$ charge collection region narrower than before irradiation, but still $40 \mu\text{m}$ at 300 V

Radiation hardening of D-CMOS

Charge collection profile, LFoundry (2000 Ωcm)

Reactor neutrons, fluence steps: 1e14, 5e14, 1e15, 2e15, 5e15



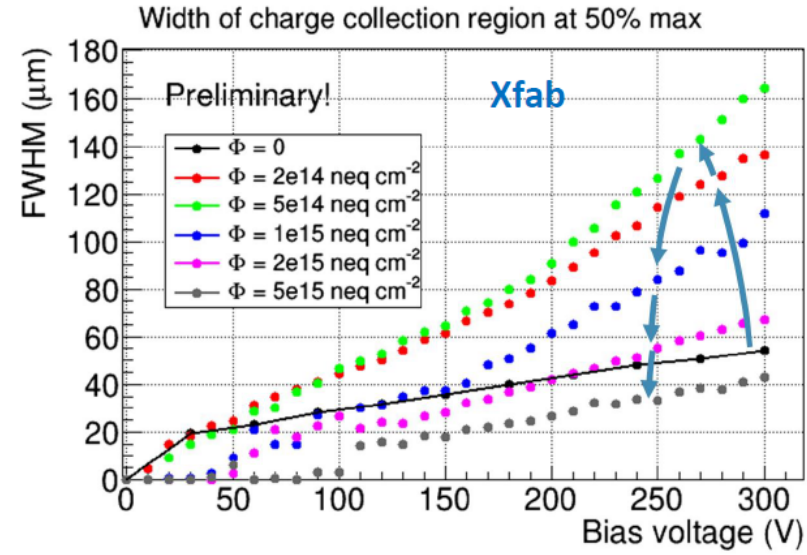
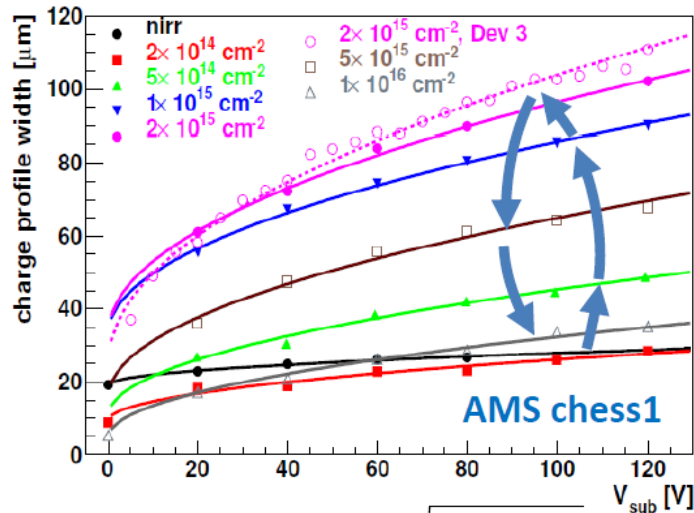
I. Mandic

Some consequence of the relatively low resistivity of CMOS wafer substrates. It can impact on sensor performance at low/intermediate irradiation levels.

- no increase of charge collection width after irradiation seen
- no significant difference between samples with and without back plane (BP)

Radiation hardening of D-CMOS

Charge profile width vs. bias voltage



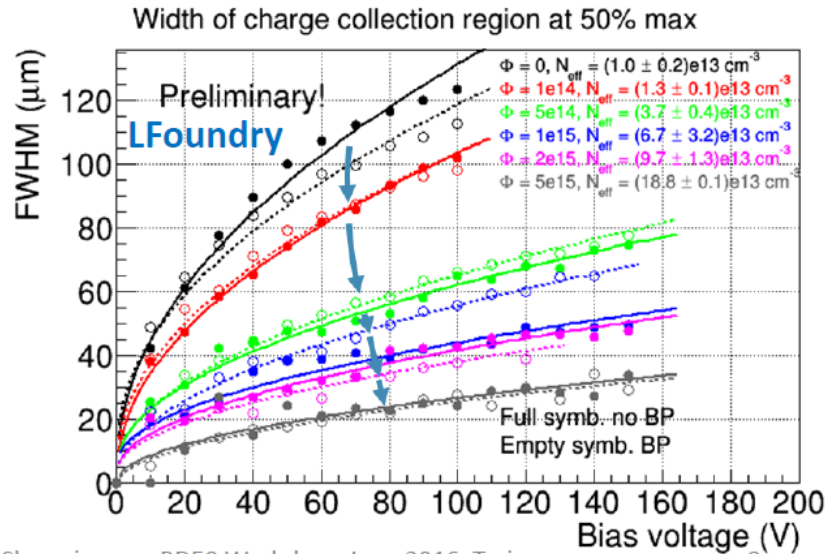
I. Mandić

$$\text{Fit: } \text{Width}(V_{bias}) = w_0 + \sqrt{\frac{2\epsilon\epsilon_0}{e_0 N_{eff}}} V_{bias}$$

w_0 and N_{eff} free parameters
 → works for AMS and LFoundry

X-FAB: can't fit with $\sqrt{V_{bias}}$
 → estimate N_{eff} from width at 300 V

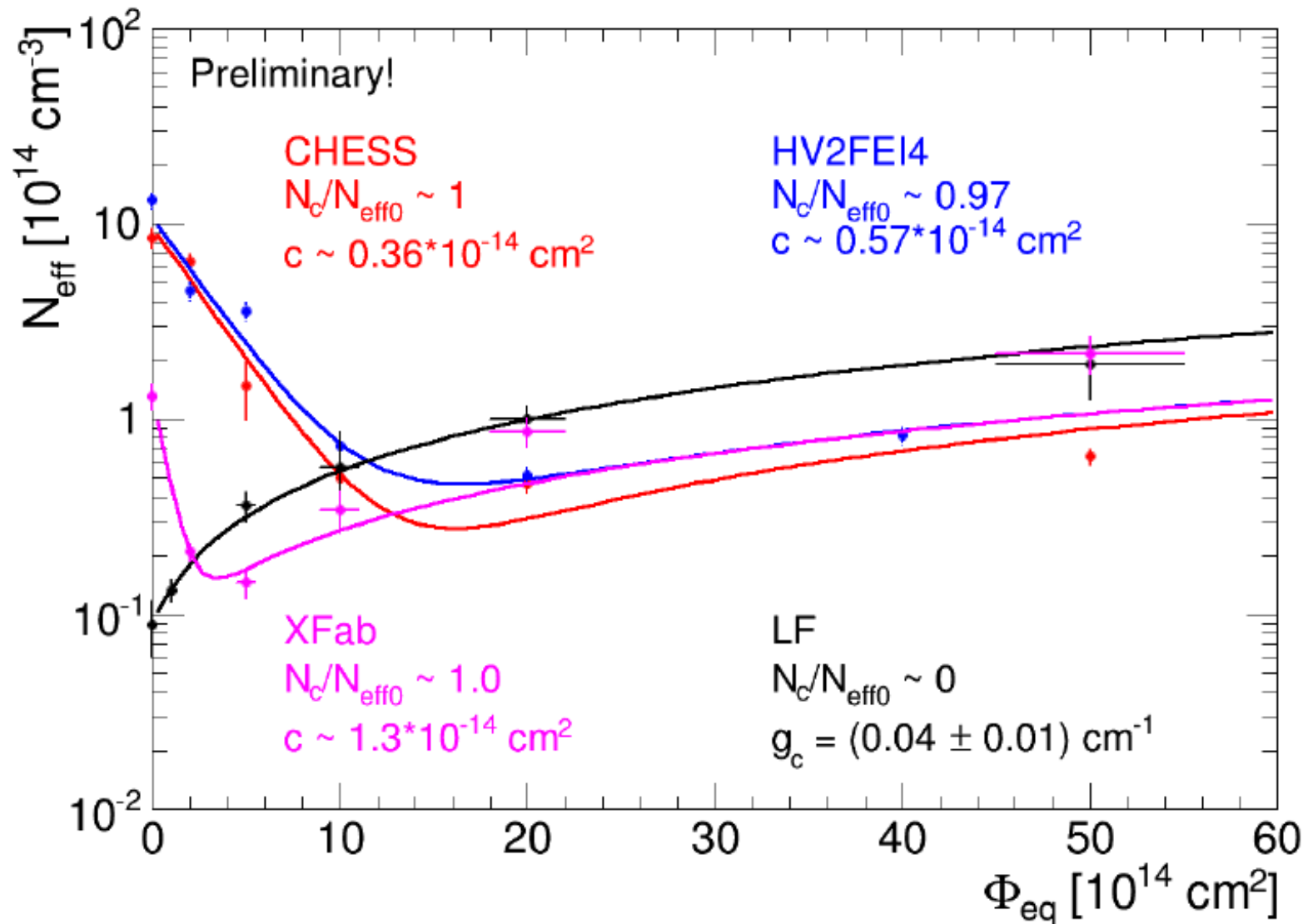
- AMS: large increase of width at low bias
- Xfab: "knee" at low bias
 0 width up to 100 V at 5e15



Igor Mandić, Jožef Stefan Institute, Ljubljana Slovenia

RD50 Workshop, June 2016, Torino

Radiation hardening of D-CMOS



AMS
(CHES and HV2FEI4)
from:
G. Kramberger et al.,
2016 *JINST11 P04007*

SUMMARY

- D-CMOS can be designed, with careful crafting of their geometry, with the ability of sustaining significantly high bias voltage, especially with the backplane bias option.
- D-CMOS can show ENC smaller than $50 e^-$, retaining therefore good S/N also after high hadron radiation fluences.
- Results are accumulating showing the tolerance of these devices, e.g. high hit efficiency after large fluences.
- The full potential of these sensors is not yet exploited, subtle design modifications are still possible to improve tolerance.
- In essence, D-CMOS are a valid option for tracking and vertexing in hadron machines